

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): John W. Jacobs and Elizabeth A. Dauch
Assignee: NEC Electronics America, Inc.
Title: TUNGSTEN PLUG CORROSION PREVENTION METHOD
USING GAS SPARGED WATER
Application No.: Unassigned Filing Date: Herewith
Examiner: Unassigned Group Art Unit: Unassigned
Docket No.: NEC0253US

Austin, Texas
October 28, 2003

MAIL STOP PATENT APPLICATION
COMMISSIONER FOR PATENTS
P. O. BOX 1450
ALEXANDRIA, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT
37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

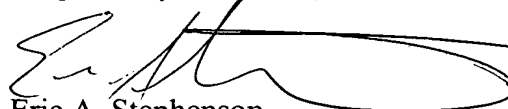
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2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

EXPRESS MAIL NUMBER:

EV 304 737 514 US

Respectfully submitted,



Eric A. Stephenson
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Reg. No. 38,321

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Application No.	
					NEC0253US		Unassigned	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					John W. Jacobs and Elizabeth A. Dauch			
					Filing Date		Group	
					Herewith		Unassigned	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,077,762	Jun. 20, 2000	Liang et al.	438	593		
	AB	6,153,531	Nov. 28, 2000	Bothra et al.	438	745		
	AC							
	AD							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AE							
	AF							
	AG							
	AH							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AI	Bothra, S., H. Sur and V. Liang, "A New Failure Mechanism by Corrosion of Tungsten in a Tungsten Plug Process," Technology Development, VLSI Technology, Inc., San Jose, California, 95131; 1998 IEEE.						
	AJ							
	AK							
	AL							
	AM							
	AN							
	AO							
	AP							
Examiner					Date Considered			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								